



PATENT
97-CT-174

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
RAFFAELE ZAMBRANO
Serial No.: 09/191,743
Filed: November 13, 1998
For: IN-SITU DEPOSITION AND
DOPING PROCESS FOR POLY-
CRYSTALLINE SILICON LAYERS
AND THE RESULTING DEVICE

Group Art Unit: 2815

Examiner: C. Whitehead

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AMENDMENT AND ELECTION

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

In response to the Office Action dated April 19, 1999, the due date for response to which has been extended to June 19, 1999 by the enclosed petition for extension of time, in connection with the above-identified application, please enter and consider the following amendment and remarks.

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to: Assistant Commissioner for Patents,

Washington, D.C. 20231, on 6/18/99
Date of Deposit

Stephen Bongini
Applicant, Assignee, or Representative

Stephen Bongini 6/18/99
Signature Dated